Form PTO 1449 (Modified)	49 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			ATTY DOCKET NO. 293375US26PCT	SERIAL NO. 10/585,732			
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LIST OF	DEEE	RENCES CITED BY APP	U ICANT	APPLICANT Tookio HASECANNA				
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				FILING DATE		GROUP		
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U.S. PATENT DOCUMENTS								
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS		
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	AW	Hirotaka HAMAMURA, et al., "TiN Films Prepared by Flow Modulation Chemical Vapor Deposition Using TiCl₄ and NH₃", Japanese Journal of Applied Physics, Vol. 40, No. 3A, Part 1, XP001078015, March 1, 2003, pages 1517-1521						
	AX					·		
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	AZ				Additional References sheet(s) attached			
Examiner					Date Considered			
*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								